

ASPEN 2013 (Taipei)

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Foreword

ASPEN 2013 (Taipei)

Guest Editors

Kuang-Chao Fan

National Taiwan University,
Taiwan (Chairman of ASPEN
2013)

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This special feature contains selected papers from the 5th International Conference of the Asian Society for Precision Engineering and Nanotechnology (ASPEN 2013) held at National Taiwan University, Taipei, Taiwan. The conference was organized as a union of academic and industrial societies in Asia to promote networking and collaboration among researchers, scientists and industrialists. From more than 350 submissions, 282 full papers were selected for presentation at the conference in oral or poster sessions. Among these papers, 35 selected papers were exclusively recommended to the journal *Measurement Science and Technology* for further review and possible publication. Such publication will extend knowledge and advances in precision engineering measurements.

The conference was steered by the Board Committee of ASPEN, which is a united society of regional societies including Japan Society for Precision Engineering (JSPE), Korean Society for Precision Engineering (KSPE), Precision Engineering Committee of Chinese Society of Mechanical Engineering in Taiwan (CSME) and Chinese Mechanical Engineering Society in China (CMES), and the related groups from Hong Kong and Singapore. The ASPEN started in Shenzhen, China in 2005. The second conference was held in Gwangju, Korea in 2007, the third in Kitakyushu, Japan in 2009, and the fourth in Hong Kong in 2011.

This special feature collects 14 papers finally accepted after a rigorous review process. These papers present recent measurement advances in the field of precision engineering and nanotechnologies, including machine tool metrology, coordinate measuring machines, optical measurement of microstructures, scanning probe microscopes, wafer measurement and testing of a large telescope mirror. It is therefore valuable to commercial sectors, research engineers, research students and academics in the field.

The Organizing Committee is particularly grateful to all of the contributors without whom this special feature would not have become reality. As the guest editors, we wish to acknowledge all the reviewers for their careful evaluation and valuable suggestions to the contributing papers. Special thanks also go to the publishing team of *Measurement Science and Technology*.